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Attorney Docket: 061063-0356139  
Client Reference: OSP-19398

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:  
MASATAKA HOURAI , ET AL.  
Application No.:

Confirmation Number:  
Group Art Unit:

Filed: Examiner:

Title: SILICON WAFER, METHOD FOR MANUFACTURING THE SAME AND METHOD  
FOR GROWING SILICON SINGLE CRYSTALS

PRELIMINARY AMENDMENT

Mail Stop Non-Fee Amendments  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In U.S. National Phase Application of International Application No.  
PCT/JP2005/015346, please amend the above-identified application as follows: